

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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Applicant(s): BIELLAK, STEVE; STOKOWSKI, STANLEY E., VAEZ-IRAVANI, MEHDI  
Assignee: KLA-TENCOR TECHNOLOGIES CORPORATION  
Title: SYSTEM AND METHODS FOR A WAFER INSPECTION SYSTEM USING MULTIPLE ANGLES AND MULTIPLE WAVELENGTH ILLUMINATION  
Application No.: 09/891,693 Filing Date: June 26, 2001  
Examiner: Hao Q. Pham Group Art Unit: 2877  
Docket No.: M-10693 US

San Francisco, California  
February 27, 2003

BOX DAC  
COMMISSIONER FOR PATENTS  
Washington, D.C. 20231

INFORMATION DISCLOSURE STATEMENT

RECEIVED

MAR 07 2003

OFFICE OF PETITIONS

Dear Sir:

Pursuant to 37 C.F.R. § § 1.56, 1.97 and 1.98, Applicants wish to call the documents listed on the enclosed Form PTO-1449 to the Examiner's attention for the above-identified patent application. Copies of the listed documents are enclosed.

Citation of the above documents shall not be construed as:

1. an admission that the documents are necessarily prior art with respect to the instant invention; or
2. an admission that the information cited herein is, or is considered to be, material to patentability as defined in § 1.56(b).

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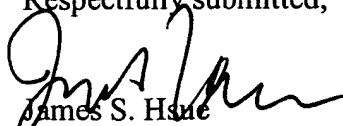
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A check in the amount of \$180.00 is enclosed as prescribed by 37 C.F.R. § 1.17(p), as indicated in the accompanying transmittal letter.

EXPRESS MAIL LABEL NO:

EU 877118232 US

Respectfully submitted,

  
James S. Hsue  
Attorney for Applicants  
Reg. No. 29,545